

Issues on Segmented Low-Gain Avalanche Detectors (LGAD)

Hartmut F.W. Sadrozinski

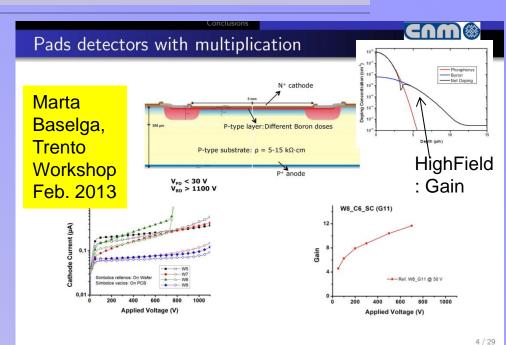
with

Vitaliy Fadeyev, Patrick Freeman, <u>Zachary Galloway</u>, Zhijun Liang, Jeffrey Ngo, <u>Colin Parker</u>, Abe Seiden, Andriy Zatserklyaniy *SCIPP, Univ. of California Santa Cruz* <u>Marta Baselga</u>, Pablo Fernández-Martínez, Virginia Greco, Salvador Hidalgo, Giulio Pellegrini, David Quirion *IMB-CNM-CSIC* <u>Nicolo Cartiglia</u>, Francesca Cenna *INFN Torino, Torino, Italy*



Low-Gain Avalanche Detector (CNM)

Run 6474 2012 ("Pablo"): Pads 300 um FZ Run 6827 2013 ("Marta"): Pads & Strips & Pixels, 10-50 um epi, 300 um FZ Run 7062 2014 ("Virginia"): Pads, 300 um FZ



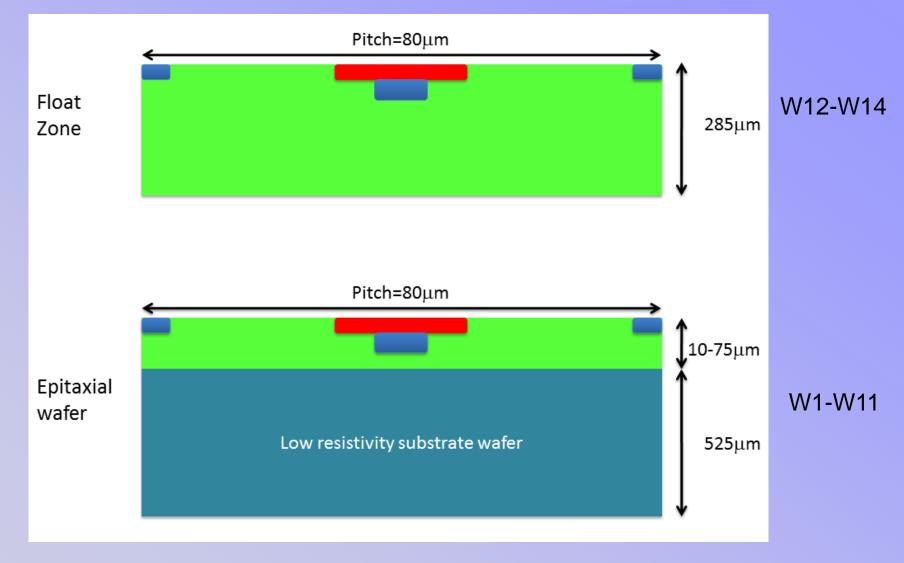
Question: what do we know about

charge multiplication on segmented LGAD?

- Characteristics of Strips from Run 6827
- Gain from TCT
- Doping Concentration from C-V
- Simulations
- Explore Alternative Configurations



Wafer Options Run 6827





Run 6827 LGAD Strips

Pitch p=80 µm

	Strip w [µm]	Metal [µm]	P-implant [μm]	w/p	P-implant /pitch	
AC1	24	20	6	0.3	7.5%	
AC2	24	24	6	0.3	7.5%	
AC3	24	28	6	0.3	7.5%	
AC4	48	44	30	0.6	37.5%	
AC5	48	48	30	0.6	37.5%	
AC6	48	52	30	0.6	37.5%	
AC7	62	58	44	0.775	55%	
AC8	62	62	44	0.775	55%	
AC9	62	66	44	0.775	55%	
AC10/AC1 1/DC	32	40	14	0.4	17.5%	

In addition pixels, and pads with and without gain



Breakdown Voltages (strips) Run 6827

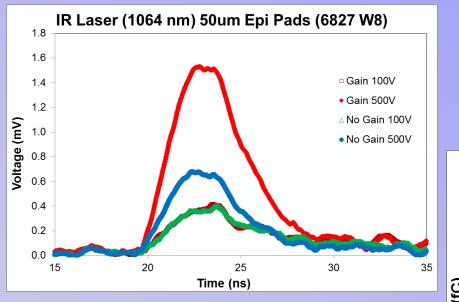
Wafer	1	4	5	6	8	9	10	11	12	13	14
	Ері	Ері	Ері	Ері	Ері	Ері	Ері	Ері	FZ	FZ	FZ
	10	10	50	50	50	75	75	75	300	300	300
	Sh	St	Sh	St	D	Sh	St	D	Sh	St	D
AC1	5	70	20	60	100	20	5	140	20	200	60
AC2	5	70	25	20	120	25	15	160	20	200	150
AC3	5	10	5	10	160	5	5	110	20	200	150
AC4	5	5	10	10	140	20	5	120	20	140	150
AC5	5	5	5	10	160	20	5	160	20	140	150
AC6	5	5	5	10	160	20	5	150	20	140	60
AC7	5	5	5	10	60	5	5	60	20	80	150
AC8	5	5	5	10	20	5	5	60	20	80	150
AC9	5	5	5	10	40	5	5	60	20	80	150
AC10	5	10	5	10	160	5	5	160	20	5	150
AC11	5	5	5	10	100	20	5	100	20	100	150
FDV				\rightarrow	200			<mark>></mark> 450		80	

Epi: 100 Ω-cm, FZ 15 kΩ -cm

D = Deep implant seems to afford higher break-down voltage, but at same gain? N.B: Break-down voltage of pad sensors > 500V typically



IR Laser Injection in epi 50 µm pads

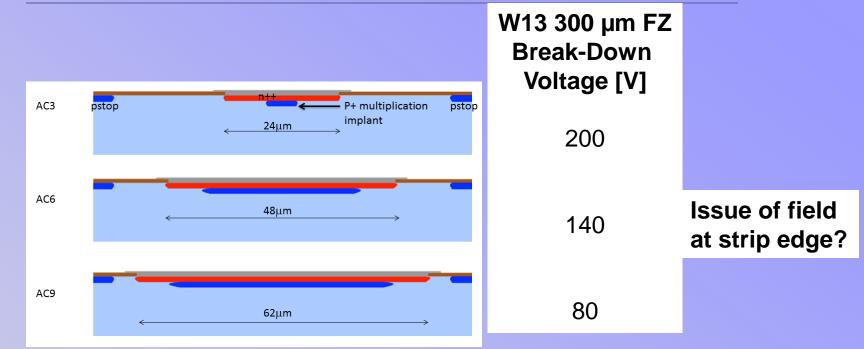


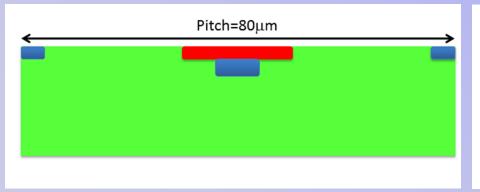
Comparison of LGAD and no-gain pads reveals gain starts at bias of 150V. This is close to the break-down voltage of the strip sensors!

IR 1064nm, 50um Epi Pads (6827 W8) 16 **VFD = 170V** 14 W8 BD3 Gain Collected Charge (fC) ▲ W8 BD4 No Gain 4 2 0 100 200 400 0 300 500 600 Bias Voltage (V)



Issues for 6827 Strip LGAD



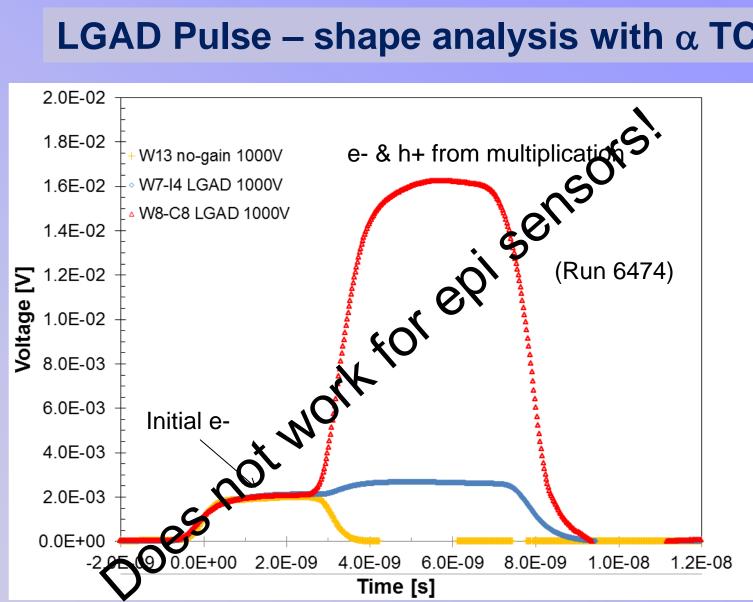


Uniformity of Response

(p-layer covers between 7.5% and 55% of pitch: what fraction of e- are traversing it and are multiplied?) Simulations Charge collection



LGAD Pulse – shape analysis with α TCT



Gain = Total pulse area / Initial Pulse Area

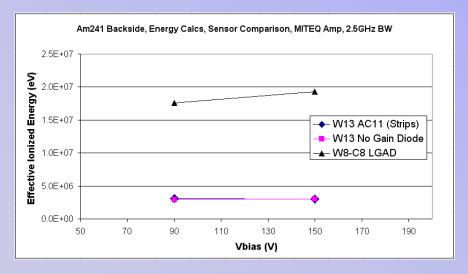
Gain is characterized by late collection of holes from multiplication



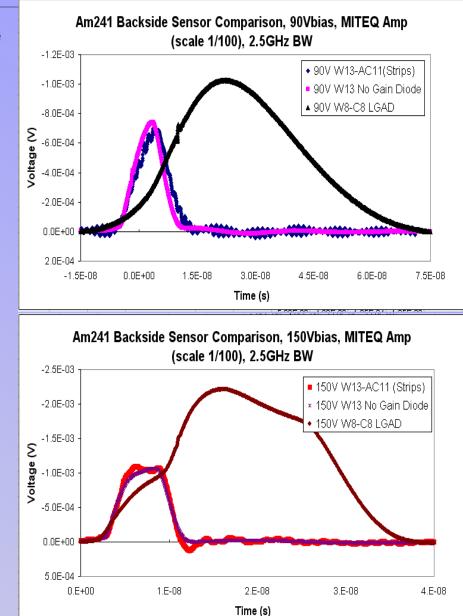
Sensor Comparison 6474 vs. 6827

Pulse shapes for 6827-W13 are comparable for no-gain pads and "gain" strip sensor -> No gain observed!

Large difference to LGAD pad (6474-W8) which exhibits the characteristic late hole signal.



6474-W8 pulses are huge compared to W13 ones, even at low bias (fields).





Investigation of the Doping Profile from C-V

(strictly correct only for pad sensors and uniform doping density!!)

Bias Voltage V – Depleted Region x :

Resistivity ρ – Doping density N :

$$V = \frac{qN}{2\varepsilon\varepsilon_0} x^2$$
$$\rho = \frac{1}{q\mu N}$$

Capacitance C – Depl. Region x : $C(x) = \varepsilon \varepsilon_0 \frac{A}{x} = A \sqrt{\frac{\varepsilon \varepsilon_0 qN}{2V}}, \Rightarrow x = A / C$

Doping Density:

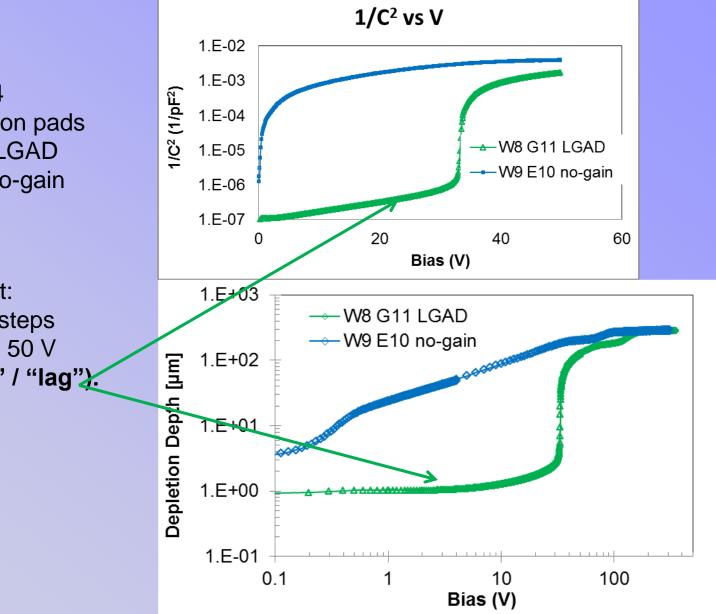
$$N = \frac{2}{\frac{d(1/C^2)}{dV}} \bullet \frac{1}{\varepsilon \varepsilon_0 q A^2} = \frac{2}{\frac{d(1/C^2)}{dV}} \bullet \frac{1}{1.6 \cdot 10^{-7} A^2}$$

Large C-V Difference LGAD/no-gain at low Bias

Run 6474 Example on pads W8G11: LGAD W9E10 no-gain

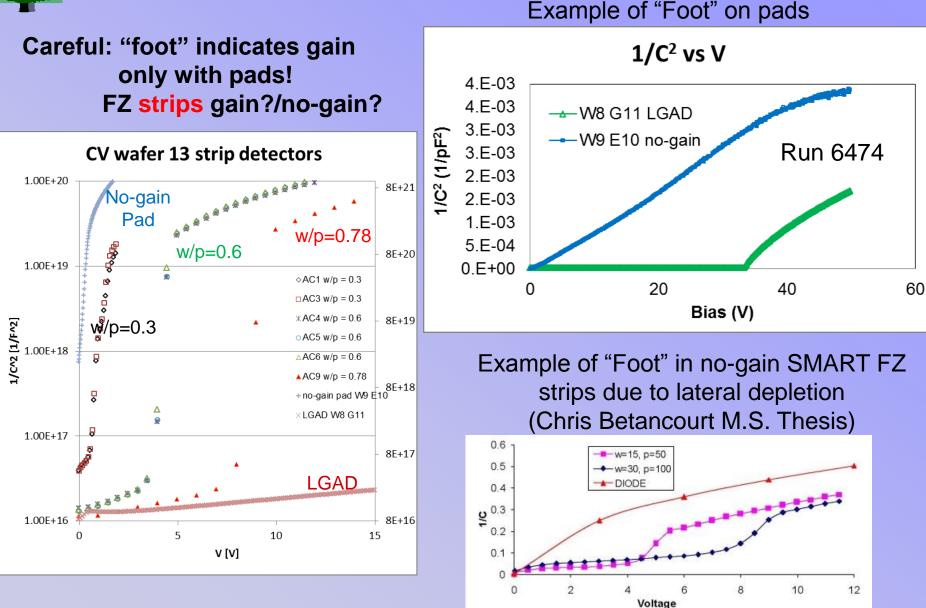
SCIPP

Important: Take voltage steps of 0.1V below 50 V (below the "foot" / "lag"



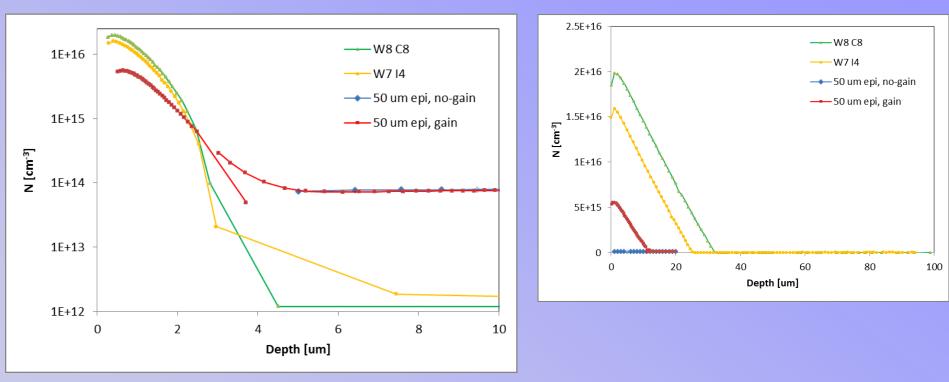


Large Voltage "Lag" due to Strip Geometry





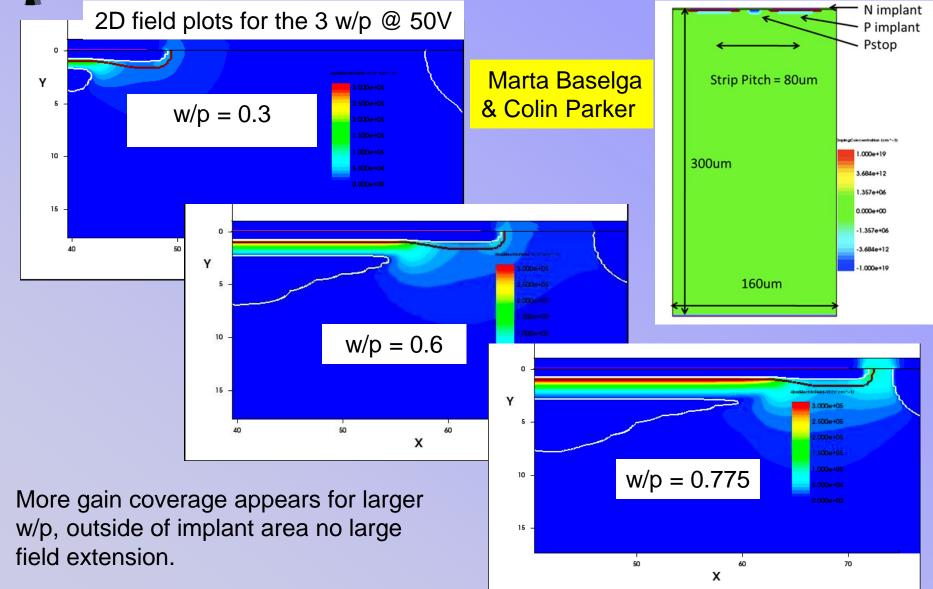
Doping Density Profile



Device	Voltage Lag [V]	N _{max} [cm ⁻³]	N _{Bulk} [cm ⁻³]	Gain (400V)
W8 C8 FZ (6474)	35	2.0e16	1.6e12	8
W7 I4 FZ (6474	29	1.6e16	1.6e12	2.5
50um epi (gain)	14	0.6e16	7e13	~ 1.7
50um epi (no-gain)	< 1	7e13	7e13	1

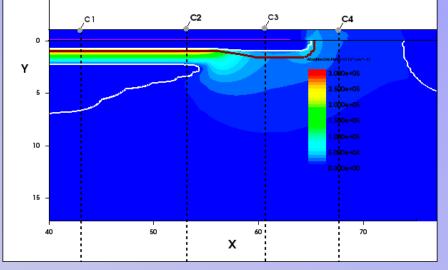


2D Field Simulation -> Gain Uniformity



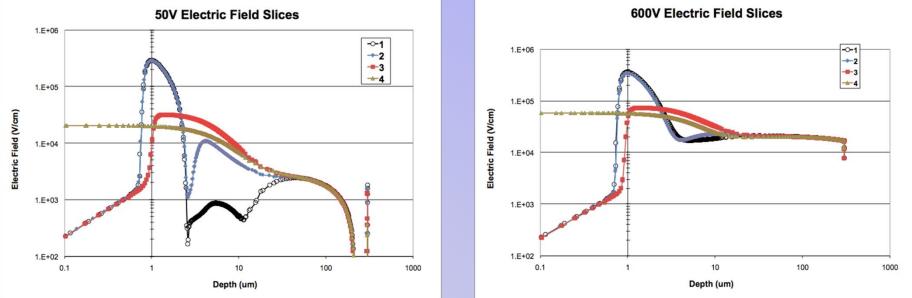


Field Slices for w/p =0.6



Electric field magnitude along 4 slices show large differences in the electric field across the pitch, suggesting also large difference in gain in those areas.

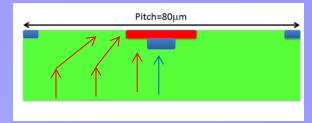
Marta and Colin are working on extracting the 2D field map to predict the electric field vectors and the charge multiplication along different electron paths (to be merged with "Weightfield").

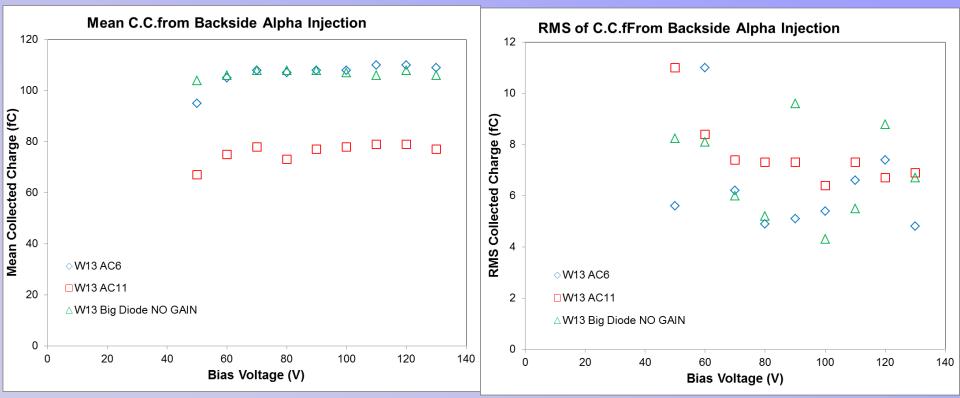




Two types of pulses: gain/no-gain?

Partial coverage of the strip with the p+ multiplication layer should lead to two distinct pulse shapes: Turn-on of multiplication with bias should increase both the mean and the RMS of the collected charge.

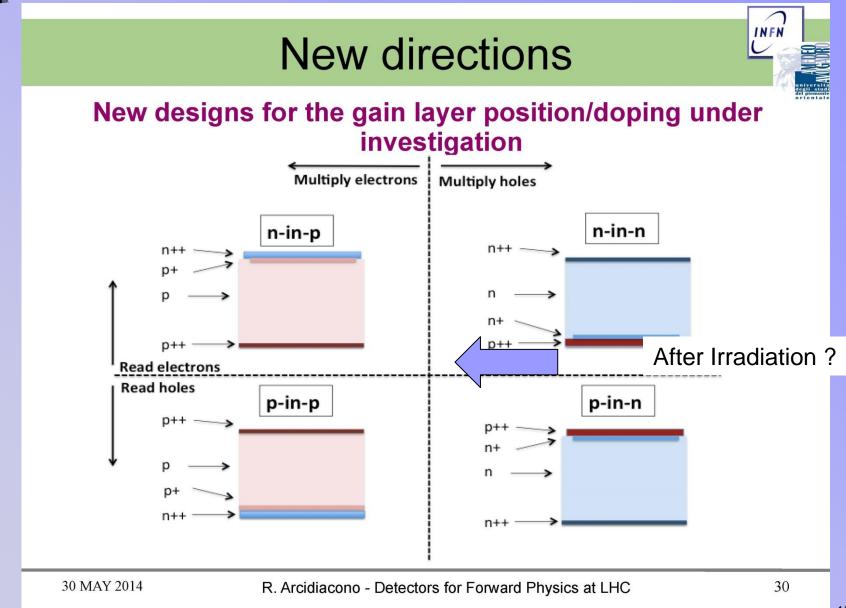




No increase in pulse mean and RMS observed for strips: no observable gain before breakdown.



Separate the Collection and the Gain





Pulse shapes for the 4 types of sensors with gain

4 sensor types: n & p bulk and n & p strip implants.
Combine two things which are proven to work:
Gain is always on an non-segmented p-n junction (like LGAD pads)
Charge collection is on the segmented ohmic side (like n-on-n strips)

Use **Weightfield** 2.1 settings, MIP 3 strips, pitch = 80 µm, width 30 µm "gain" = 2 and 3, h/e = 0.03 Scope BW = 2.5 GHz (black curves)

Thickness 30 µm: bias = 100, 150V, VFD = 20V 50 µm: bias = 200, VFD = 30V 300 µm: bias = 1000, VFD = 80V Developed by Nicolo Cartiglia.

Need to merge it with 2D field simulations.

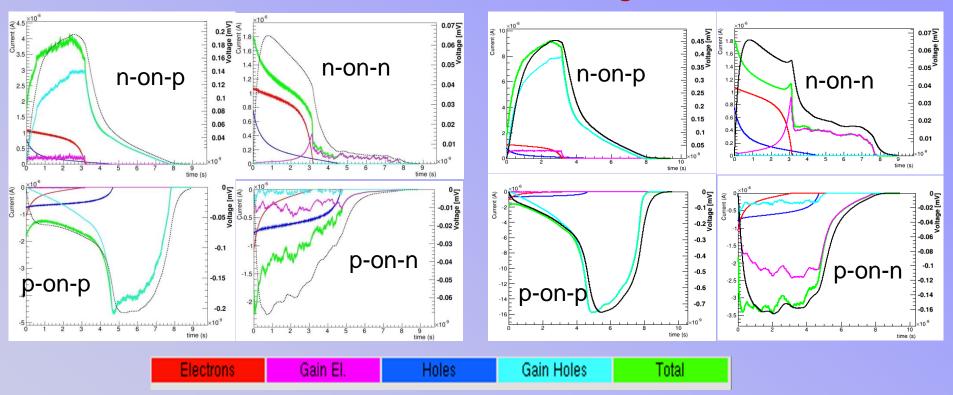
Investigate the relation between gain and slew rate for timing.



Pulse shapes for MIP in 300 µm LGAD

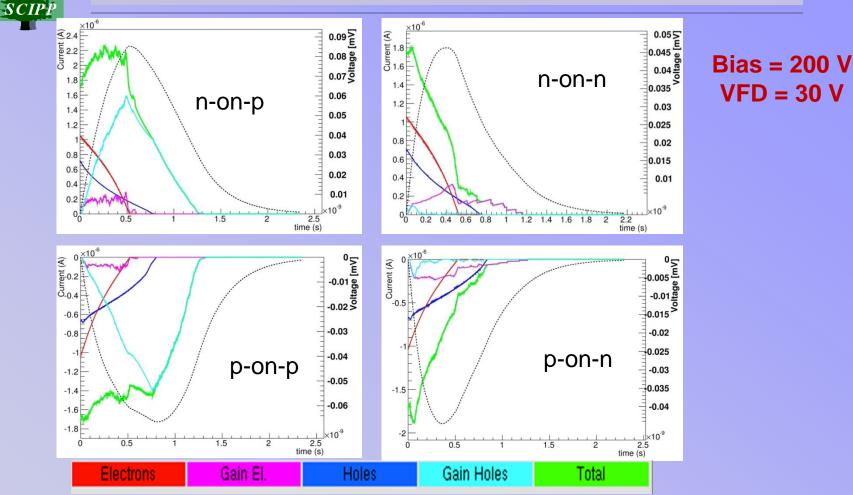
gain = "2"

gain = "3"



Thick p-type LGAD rely on late hole collection: p-on-p not viable. Thick n-type LGAD rely on much smaller hole multiplication (with a fast p-on-n).



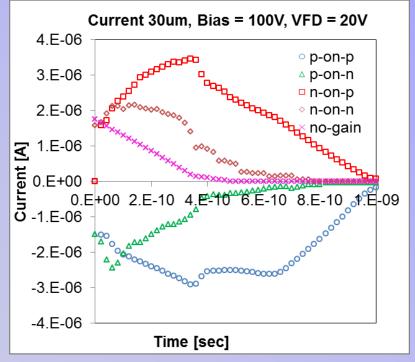


The no-gain pulse (sum of red and dark blue) is very fast. A thin LGAD needs a fair amount of gain to improve on the fast no-gain pulse!

Thin p-on-p LGAD might be viable, although the holes are more delayed than in n-on-p.



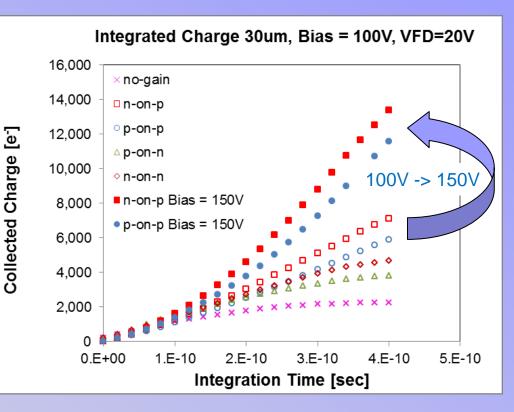
Slew Rate dQ/dt is F.o.M. for Time Resolution



Thin p-on-p LGADs look viable, especially with large gain:

Charge	[ke ⁻] wi	thin 400ps	
Bias:	100V	150V	
p-on-p	5.9	11.6	
n-on-p	7.1k	13.4	
n-on-n	2.3 (no-gain)		

100V	150V
2.3	
1.9	
5.5	11.5
5.2	10.5
	2.3 1.9 5.5





Conclusions from Run 6827

- Segmented sensors from Run 6827 show very low gain attributable to low doping density of the p-implant layer and the low breakdown voltages.
- The important question how uniform the response is (i.e. how much the gain differs for electrons arriving at different regions of the strip) could therefor not be answered. We need a simulation program to estimate this information using 2D simulations, taking into account the doping profile.
- Scans across the strips of "Spaghetti" diodes implemented in the next run are expected to allow answering this question on a variety of strip geometries.
- To achieve uniformity of response and high bias operation in thin segmented sensors, a spatial separation of the charge collection and the gain mechanism combines two aspects which have proven to work at high bias voltage:

a) LGAD pads and b) strips on the ohmic side.

- Simulations with "Weightfield" indicate that for very thin sensors, i.e. very fast charge collection, p-on-p is a viable option.
- Since most of the signal from charge multiplication is late, a large gain (>10) is needed for fast collection in thin sensors.



Acknowledgements

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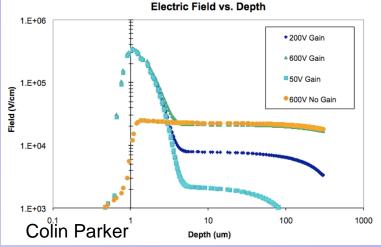


Back-up

SCIPP

Charge Collection with α 's from Am(241)

α's



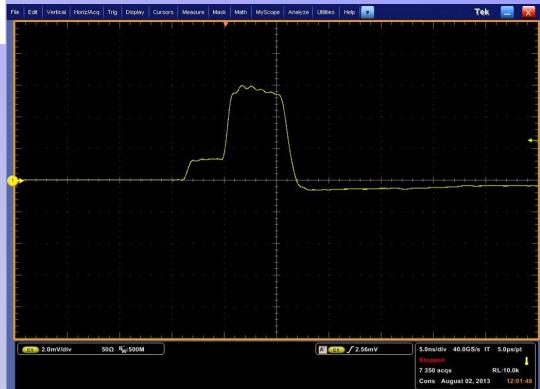
Fast signals!

Observed rise times ≈ 400 ps allowing time-resolved current transient (TCT) analysis .

Don't know yet where the lower limit is, since we are still improving the BW of the system.

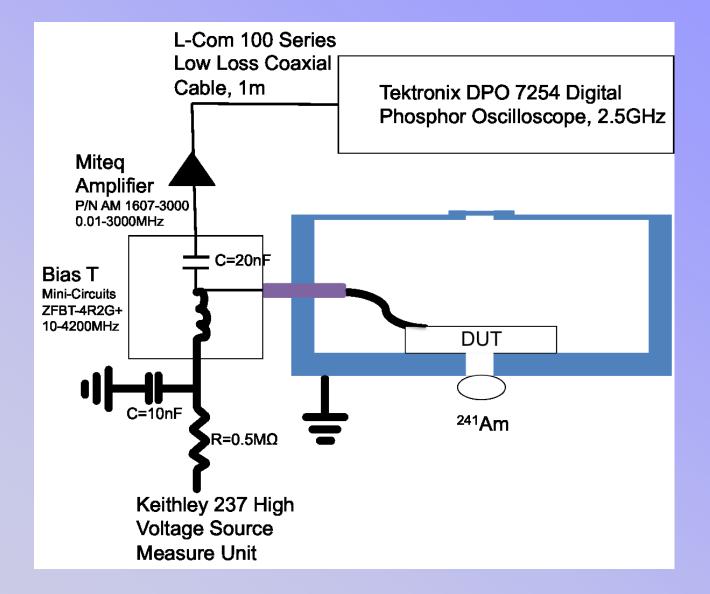
Am(241)

illuminating the back side, range ~ few um's "electron injection" signal drifts and is then amplified in high field



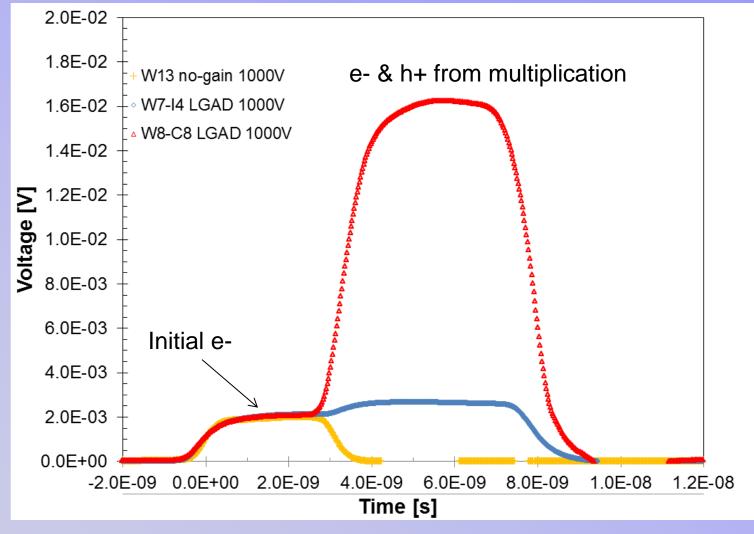


High BW α TCT Set-up





Pulse – shape analysis with α TCT

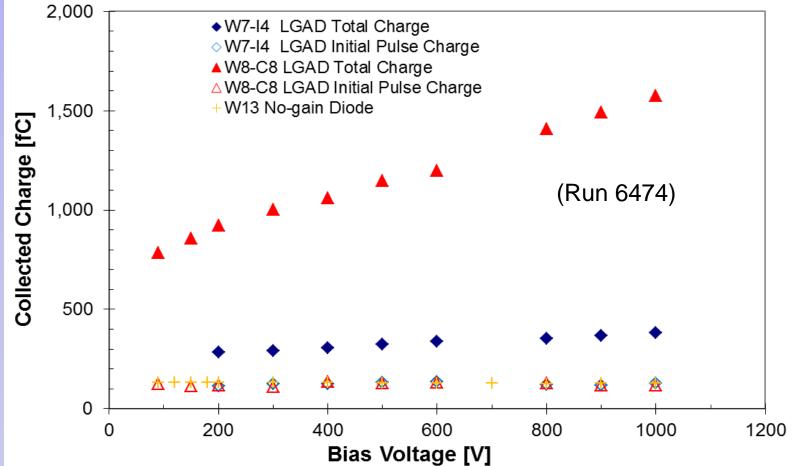


Gain = Total pulse area / Initial Pulse Area

Charge collection well described by simulations



Total charge & initial Pulse charge

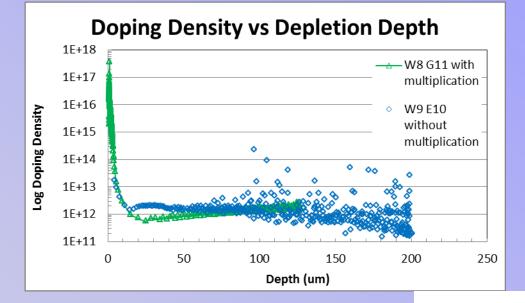


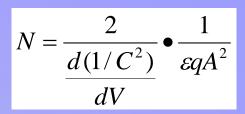
The initial pulse charge is identical for two different LGAD's (after correction) and a no-gain diode: Reflects the initial electron drift.

Large gain differences: $G(W8-C8)/G(W7-I4) \approx 4$ at 1000V bias. Original idea: correlation with high leakage current, turns out to be wrong

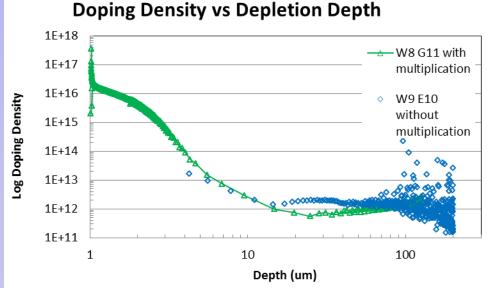


Doping Density Profile N(x)





LGAD and no-gain diode have same doping profile far away from gain region!





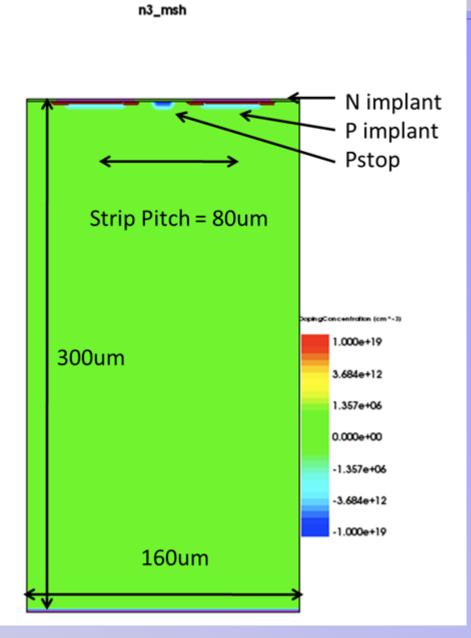
Depleted thickness x vs. V

Depleted Thickness vs. V x = A / C800.0 Conversion of 80.0 Thickness [um] capacitance $C(V) \rightarrow C(x)$ W8 G11 with multiplication doping density $N(V) \rightarrow N(x)$ W9 E10 without 8.0 resistivity $\rho(V) \rightarrow \rho(x)$ multiplication 0.8 50 100 150 200 350 0 250 300 Bias (V) 100 10 [un] x Saturates at $x \approx 250$ um as 1 expected -W7 14 Shows large voltage lag for LGAD → 50 um epi no-gain - 50um epi gain 0 5 10 15 0 20

Bias [V]



Structure Screenshot



Hartmut F.-W. Sadrozinski, Segmented LGAD, RD50 Bucharest, June 2014